

ICPE2022 Tentative Program

		28th November, 2022	
14:00		14:00-17:00 Registration desk open at Nara Prefecture Convention Center (NPCC)	
19:00		17:00-19:00 Welcome reception at DMG MORI Nara Product and Development Center (PDC) (Bus transportation NPCC-PDC is provided. 15:45-17:15)	

		29th November, 2022	
		Opening and Plenary session @ Hall A+B	
8:30		Registration desk open	
9:30		Opening speech	
9:50		Plenary speech 1	
10:10		Plenary speech 2	
11:30		Lunch @ Hall A+B	

		Technical Session	
		Registration desk open	
12:40		Room 1 @ 201 2F	Room 2 @ 202 2F
12:55	C000017	B2: Advanced grinding technologies 1: Shinya Morita (Tokyo Denki University)	C000129 C000057 C000015 C000290 C000291
13:10	C000237		A1: Digital design and manufacturing systems 1: Hanshiko Suwa (Setsunan University)
13:25	C000035		C000129 C000057 C000015 C000290 C000291
13:40	C000281		C000129 C000057 C000015 C000290 C000291
13:55	C000285		C000129 C000057 C000015 C000290 C000291
14:10			C000213
14:30			Coffee break (20 minutes)
14:50			Poster presentation (1 hour) @ Hall C
15:30			Coffee break (20 minutes)
15:50	C000204	B2: Advanced grinding technologies 2: Kazuhiko Ohashi (Okayama University)	C000223 C000234 C000236 C000062 C000052
16:05	C000270		A1: Digital design and manufacturing systems 2: Eiichi Aoyama (Doshisha University)
16:20	C000267		C000029 C000124 C000159 C000149 C000206 C000301
16:35	C000283		C1: Advanced machine tools and elements 2: Yoshiaki Morimoto (Kanazawa Institute of Technology), Akio Hayashi (Kanazawa Institute of Technology)
16:50			C000095 C000186 C000170 C000117 C000153 C000116
17:05			D1: Nano-scale measurements and calibrations 2: Tetsutake Hayashi (Kyushu University)
			C000150 C000242 C000311 C000282 C000306
			A4: CAD/CAM technologies 2: Keisuke Takasugi (Kanazawa University)
			C000011 C000064 C000093 C000027 C000089 C000122
			B1: Advanced cutting technologies 1: Hiroyuki Sasahara (Tokyo University of Agriculture and Technology)

		30th November, 2022	
		Technical Session	
		Registration desk open	
8:30		Room 1 @ 201 2F	Room 2 @ 202 2F
9:00		C000096 C000056 C000063 C000114 C000173 C000292	B4: Nano-scale surface finishings 1: Syunpei Kurakawa (Kyushu University)
9:15			A3: Advanced system design and applications 1: Koji Iwamura (Osaka Metropolitan University)
9:30			C000096 C000217 C000049 C000208 C000266 C000188
9:45			C000096 C000217 C000049 C000208 C000266 C000188
10:00			C000096 C000217 C000049 C000208 C000266 C000188
10:15			C000096 C000217 C000049 C000208 C000266 C000188
10:30			Coffee break (20 minutes)
10:50	C000074	B4: Nano-scale surface finishings 2: Hirotaka Hiyama (Ebara Corporation)	C000197 C000245 C000041 C000248 C000256
11:05	C000177		A3: Advanced system design and applications 2: Toshiyuki Kaihara (Kobe University)
11:20	C000214		C000096 C000217 C000049 C000208 C000266 C000188
11:35	C000229		C000096 C000217 C000049 C000208 C000266 C000188
11:50	C000312		C000096 C000217 C000049 C000208 C000266 C000188
12:05			C000096 C000217 C000049 C000208 C000266 C000188
12:20			Lunch (1 hour) @ Technical Session Room Hall A+B is recommended.
12:35			C000077 C000082 C000098 C000103 C000118 C000191 C000262
12:50		D3: Mechano photonics engineering and optical applications: Yutaka Ohtani (Utsunomiya University)	C000151 C000051 C000185 C000160 C000075 C000026
13:05			A2: Life cycle and smart engineering: Yusuke Kishita (The University of Tokyo)
13:20			C000096 C000217 C000049 C000208 C000266 C000188
13:35			C000096 C000217 C000049 C000208 C000266 C000188
13:50			C000096 C000217 C000049 C000208 C000266 C000188
14:05			C000096 C000217 C000049 C000208 C000266 C000188
14:20			C000096 C000217 C000049 C000208 C000266 C000188
14:35			C000096 C000217 C000049 C000208 C000266 C000188
14:50			C000096 C000217 C000049 C000208 C000266 C000188
15:05			Coffee break (15 minutes)

		Plenary Session @ Hall A+B	
15:20		Plenary speech 3	
16:10		Plenary speech 4	
		Banquet @ Hotel Nikko Nara	
17:00		Bus transportation from NCC to Hotel Nikko Nara is provided.	
18:30		Banquet @ Hotel Nikko Nara	

		1st December, 2022	
		Technical Session	
		Registration desk open	
8:30		Room 1 @ 201 2F	Room 2 @ 202 2F
9:00		C000047 C000007 C000045 C000046 C000063	B6: Energy beam processings 1: Yoshiaki Nakazato (Nippon Institute of Technology)
9:15			C000047 C000007 C000045 C000046 C000063
9:30			C000047 C000007 C000045 C000046 C000063
9:45			C000047 C000007 C000045 C000046 C000063
10:00			C000047 C000007 C000045 C000046 C000063
10:15			C000047 C000007 C000045 C000046 C000063
10:30			Coffee break (20 minutes)
10:45			C000047 C000007 C000045 C000046 C000063
10:55	C000112	C2: Micro systems and machine elements 2: Masato Mizukami (Muroran Institute of Technology)	C000044 C000178 C000199 C000303 C000148
11:10	C000201		B6: Energy beam processings 2: Yasuhiro Okamoto (Okayama University)
11:25	C000269		C000044 C000178 C000199 C000303 C000148
11:40			C000044 C000178 C000199 C000303 C000148
11:55			C000044 C000178 C000199 C000303 C000148
12:10			C000044 C000178 C000199 C000303 C000148
12:25			C000044 C000178 C000199 C000303 C000148
12:40			Lunch (1 hour) @ Technical Session Room
12:55			C000157 C000205 C000156 C000172 C000179
13:10		F1: Advanced surface processings 1: Hiroaki Kakuchi (Osaka University)	C000141 C000161 C000222 C000225 C000228
13:25			B3: Micro/Nano machining and figuring 1: Hirotami Suzuki (Chubu University)
13:40			C000141 C000161 C000222 C000225 C000228
13:55			C000141 C000161 C000222 C000225 C000228
14:10			C000141 C000161 C000222 C000225 C000228
14:25			C000141 C000161 C000222 C000225 C000228
14:40			C000141 C000161 C000222 C000225 C000228
14:55			C000141 C000161 C000222 C000225 C000228
15:10	C000084	F1: Advanced surface processings 2: Yoshifumi Suzuki (Kagawa University)	C000018 C000055 C000198 C000235 C000313
15:25	C000126		B3: Micro/Nano machining and figuring 2: Yan Jiwang (Kobe University)
15:40	C000137		C000018 C000055 C000198 C000235 C000313
15:55	C000020		C000018 C000055 C000198 C000235 C000313
16:10			C000018 C000055 C000198 C000235 C000313
16:25			C000018 C000055 C000198 C000235 C000313